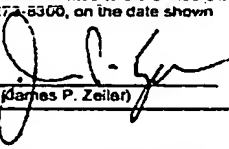


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Patent and Trademark Office, Fax No. (571) 273-8300, on the date shown

Dated: December 18, 2006 Signature: 

James P. Zeilan

**EXPEDITED PROCEDURE
Art unit 2822**Docket No.: 29936/39764
(PATENT)**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**In re Patent Application of:
Cha Deok Dong

Application No.: 10/720,457

Confirmation No.: 4077

Filed: November 24, 2003

Art Unit: 2822

For: Method for Forming Device Isolation Film in
Semiconductor Device

Examiner: M. M. Trinh

AMENDMENT AFTER FINAL ACTION UNDER 37 C.F.R. 1.116MS AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

In response to the official action dated October 18, 2006, finally rejecting
claims 1-14, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins
on page 2 of this paper.

Remarks/Arguments begin on page 3 of this paper.

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